

<b>TRANSMITTAL FORM</b> <i>(to be used for all correspondence after initial filing)</i>	Application Number	10/632,662	
	Filing Date	August 1, 2003	
	First Named Inventor	Barrett, Ronald W.	
	Art Unit		
	Examiner Name		
Total Number of Pages in This Submission		Attorney Docket Number	019930-003110US

ENCLOSURES (Check all that apply)		
<input type="checkbox"/> Fee Transmittal Form <input type="checkbox"/> Fee Attached <input type="checkbox"/> Amendment/Reply <input type="checkbox"/> After Final <input type="checkbox"/> Affidavits/declaration(s) <input type="checkbox"/> Extension of Time Request <input type="checkbox"/> Express Abandonment Request <input checked="" type="checkbox"/> Information Disclosure Statement <input type="checkbox"/> Certified Copy of Priority Document(s) <input type="checkbox"/> Response to Missing Parts/Incomplete Application <input type="checkbox"/> Response to Missing Parts under 37 CFR 1.52 or 1.53	<input type="checkbox"/> Drawing(s) <input type="checkbox"/> Licensing-related Papers <input type="checkbox"/> Petition <input type="checkbox"/> Petition to Convert to a Provisional Application <input type="checkbox"/> Power of Attorney, Revocation Change of Correspondence Address <input type="checkbox"/> Terminal Disclaimer <input type="checkbox"/> Request for Refund <input type="checkbox"/> CD, Number of CD(s)	<input type="checkbox"/> After Allowance Communication to Group <input type="checkbox"/> Appeal Communication to Board of Appeals and Interferences <input type="checkbox"/> Appeal Communication to Group (Appeal Notice, Brief, Reply Brief) <input type="checkbox"/> Proprietary Information <input type="checkbox"/> Status Letter <input checked="" type="checkbox"/> Other Enclosure(s) <i>(please identify below):</i> Return Postcard, copy of one (1) cited reference
Remarks		The Commissioner is authorized to charge any additional fees to Deposit Account 20-1430.

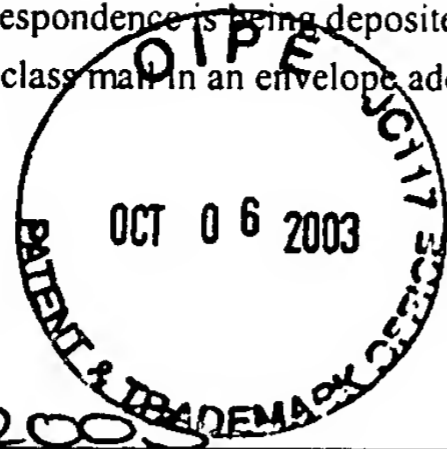
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On Oct. 2, 2003

TOWNSEND and TOWNSEND and CREW LLP

By: [Signature]  
Nicola M. Wartell

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of:

Bevan Staple et al.

Application No.: 10/632,662

Filed: August 1, 2003

For: SYSTEMS AND METHODS FOR  
OVERCOMING STICTION USING A  
LEVER

Examiner:

Art Unit:

INFORMATION DISCLOSURE  
STATEMENT UNDER 37 CFR §1.97 and  
§1.98

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Sir:

The references cited on attached form PTO/SB/08A and PTO/SB/08B are being called to the attention of the Examiner. In accordance with 37 CFR §1.98(d), copies of many of the references can be found in Application No. 09/898,988, filed 07/03/2001 (Attorney Docket No. 019930-003100US). All other U.S. patents are not enclosed in accordance with the Patent Office waiver issued August 5, 2003 in the Official Gazette, which states as follows:

The Office hereby waives the requirement under 37 CFR 1.98

(a)(2)(i) for submitting a copy of each cited U.S. patent and each U.S.

patent application publication for all U.S. national patent

applications filed after June 30, 2003 and for all international applications that have entered the national stage under 35 USC 371 after June 30, 2003. See 37 CFR 1.491(b). For all patent applications filed on or before June 30, 2003, copies of cited U.S. patents and patent application publications are still required unless an eIDS is filed.

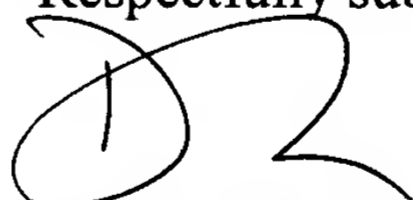
In accordance with 37 CFR 1.98(a)(2), a copy of the C28, a non-patent literature reference, is enclosed.

It is respectfully requested that the cited references be expressly considered during the prosecution of this application, and the references be made of record therein and appear among the "references cited" on any patent to issue therefrom.

As provided for by 37 CFR 1.97(g) and (h), no inference should be made that the information and references cited are prior art merely because they are in this statement and no representation is being made that a search has been conducted or that this statement encompasses all the possible relevant information.

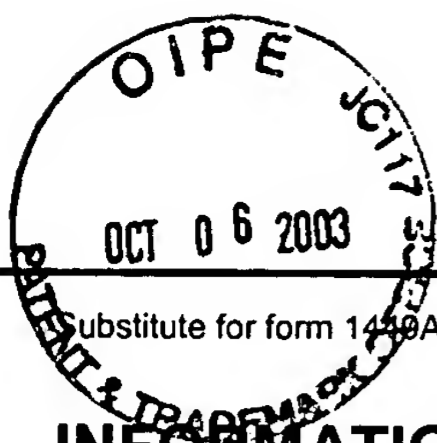
Applicant believes that no fee is required for submission of this statement. However, if a fee is required, the Commissioner is authorized to deduct such fee from the undersigned's Deposit Account No. 20-1430. Please deduct any additional fees from, or credit any overpayment to, the above-noted Deposit Account.

Respectfully submitted,



Douglas M. Hamilton  
Reg. No. 47,629

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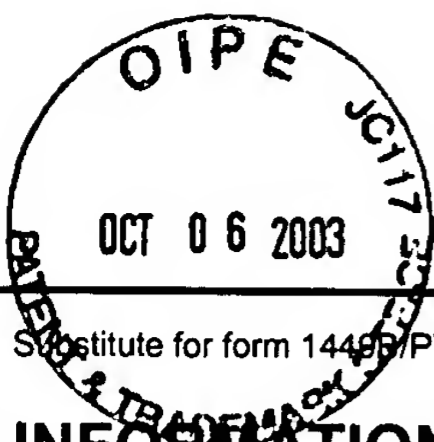


<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  (use as many sheets as necessary)		<b>Complete if Known</b>	
		Application Number	10/632,662
		Filing Date	August 1, 2003
		First Named Inventor	Staple, Bevan
		Art Unit	
Examiner Name		Attorney Docket Number	019930-003110US
Sheet	1	of	3

U.S. PATENT DOCUMENTS+					
Examiner Initials*	Cite No. <sup>1</sup>	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number Kind Code <sup>2</sup> (if known)			
	A1	US-4,330,175	05-18-1982	Yohji Fujii et al.	
	A2	US-4,733,945	03-29-1988	Bacich	
	A3	US-5,061,049	10-29-1991	Hornbeck	
	A4	US-5,117,311	05-26-1992	Nomura	
	A5	US-5,212,582	05-18-1993	William E. Nelson	
	A6	US-5,279,924	01-18-1994	Keiji Sakai et al.	
	A7	US-5,392,151	02-21-1995	Nelson	
	A8	US-5,414,540	05-09-1995	Patel et al.	
	A9	US-5,493,452	02-20-1996	Hoshino et al.	
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	A12	US-5,602,671	02-11-1997	Hornbeck	
	A13	US-5,757,559	05-26-1998	Nomura et al.	
	A14	US-5,768,649	06-16-1998	Pearson	
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	A20	US-5,999,288	12-07-1999	Georgios Nicos Ellinas et al.	
	A21	US-5,999,672	12-07-1999	Hunter et al.	
	A22	US-6,028,689	02-22-2000	Michalicek et al.	
	A23	US-6,040,935	03-21-2000	Michalicek	
	A24	US-6,052,232	04-18-2000	Ikawa	
	A25	US-6,097,519	08-01-2000	Ford	
	A26	US-6,097,859	08-01-2000	Solgaard	
	A27	US-6,097,863	08-01-2000	Dipakbin Qasem Chowdhury	
	A28	US-6,108,471	08-22-2000	Zhang et al.	
	A29	US-6,128,122	10-03-2000	Drake et al.	
	A30	US-6,147,790	11-14-2000	Meier et al.	
	A31	US-6,220,561 B1	04-24-2001	Garcia	
	A32	US-6,263,127 B1	07-17-2001	Dragone et al.	
	A33	US-6,307,657 B1	10-23-2001	Joseph Earl Ford	
	A34	US-6,449,096 B1	09-10-2002	Fabiny et al.	
	A35	US-6,480,320 B2	11-02-2002	Nasiri	
	A36	US-6,501,877 B1	12-31-2002	Weverka et al.	
	A37	US-6,535,319 B2	03-18-2003	Buzzetta et al.	
	A38	US-6,542,653 B2	04-01-2003	Wu et al.	
	A39	US-6,614,581 B2	09-02-2003	Anderson	

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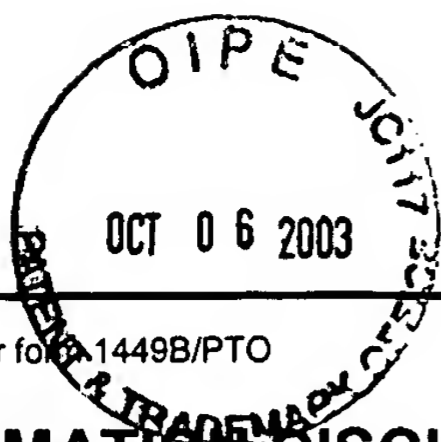
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				First Named Inventor	Staple, Bevan
				Art Unit	
				Examiner Name	
Sheet	2	of	3	Attorney Docket Number	019930-003110US

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials *	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
	C1	AKIYAMA, T. et al.; "Controlled Stepwise Motion in Polysilicon Microstructures," Journal of Microelectromechanical Systems, Vol. 2, No. 3, September 1993; pp.106-110	
	C2	ASHRUF, C.M.A. et al., "Galvanic porous silicon formation without external contacts," Sensors and Actuators 74 (1999) pp. 118-122	
	C3	BEAN, KENNETH et al., "Anisotropic Etching of Silicon," IEEE Transactions on Electron Devices, Vol. Ed-25, No. 10, October 1978	
	C4	CIARLO, DINO R. "A latching accelerometer fabricated by the anisotropic etching of (110) oriented silicon wafers," Lawrence Livermore Nat'l Laboratory, March 1, 1992	
	C5	DEWA, A.S. et al., "Development of a Silicon Two-Axis Micromirror for an Optical CrossConnect," Solid State Sensors and Actuators Workshop, Hilton Head, South Carolina, pp. 93-96	
	C6	FORD, JOSEPH et al., "Wavelength Add Drop Switching Using Tilting Micromirrors," Journal of Lightwave Technology, Vol. 17, No. 5, May 1999	
	C7	GRADE, J. et al., "A Large-Deflection Electrostatic Actuator for Optical Switching Applications, Solid-State Sensor and Actuator Workshop, Hilton Head Island, South Carolina, June 4-8, 2000; pp. 97-100	
	C8	GRAF, U.U. et al., <i>Fabrication and Evaluation Of An Etched Infrared Diffraction Grating</i> , Applied Optics, January 1, 1994, Vol. 33, No. 1, pgs. 96-102.	
	C9	HOPKINS, ROBERT E., <i>Some Thoughts On Lens Mounting</i> , Optical Engineering, September-October 1976, Vol. 15, No. 5, pgs. 428-430.	
	C10	KAAJAKARI, V. et al.; "Ultrasonic Actuation for MEMS Dormancy-Related Stiction Reduction," In MEMS Reliability for Critical Applications, Proceedings of SAPIE Vol. 4180 (2000); pp. 60-65	
	C11	KELLER, C. Dissertation entitled: Microfabricated Silicon High Aspect Ratio Flexures for In-Plane Motion, Fall 1998	
	C12	KELLER, LUKE D. et al., <i>Fabrication And Testing Of Chemically Micromachined Silicon Echelle Gratings</i> , Applied Optics, March 1, 2000, Vol. 39, No. 7, pgs. 1094-1105.	
	C13	KOCH, T.L. et al., "Anisotropically etched deep gratings for InP/InGaAsP optical devices," J.App. Phys. 62 (8), 15 October 1987	
	C14	LOEWEN, ERWIN G. et al., <i>Diffraction Gratings and Applications</i> , Marcel Dekker, Inc., New York - Basel, Chapter 4, pgs. 132-136 and Chapter 8 pgs. 300-301.	
	C15	MULLER, L. Dissertation entitled: Gimballed Electrostatic Microactuators with Embedded Interconnects, Spring 2000	
	C16	NISHI, I. et al., "Broad-Passband-Width Optical Filter for Multi-Demultiplexer Using a Diffraction Grating and a Retroreflector Prism," Electronics Letters, Vol. 21, No. 10, 9 <sup>th</sup> May 1985	

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<div>Substitute for form 1449B/PTO</div> <div>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</div> <div>(use as many sheets as necessary)</div>				<b>Complete if Known</b>	
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Sheet	3	of	3	Attorney Docket Number	019930-003110US

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Examiner Initials *	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
	C17	PHILLIPPE, P. et al., "Wavelength demultiplexer: using echelette gratings on silicon substrate," Applied Optics, Vol. 24, No. 7, 1 April 1985	
	C18	RALLISON, R. D., White Paper on: <i>Dense Wavelength Division Multiplexing (DWDM) and the Dickson Grating</i> , January 6, 2001, 9 pages.	
	C19	SCHILLING, M. et al., "Deformation-free overgrowth of reactive ion beam etched submicron structures in InP by liquid phase epitaxy," Appl. Phys. Lett. 49 (12), 22 September 1986	
	C20	SHAMS, MOHAMMAD KAZEM et al., <i>Preferential Chemical Etching Of Blazed Gratings In (110)-Oriented GaAs</i> , Optics Letters, March 1979, Vol. 4, No. 3, pgs. 96-98.	
	C21	SMITH, M.S.D. et al., <i>Diffraction Gratings Utilizing Total Internal Reflection Facets in Littrow Configuration</i> , IEEE Photonics Technology Letters, January 1, 1999, Vol. 11, No. 1, pgs. 84-86.	
	C22	SUN, Z. J. et al., Demultiplexer with 120 channels and 0.29-nm Channel Spacing," IEEE Photonics Technology Letters, Vol. 10, No. 1, January 1998	
	C23	TANG, W. et al., "Electrostatically Balanced Comb Drive for Controlled Levitation," Reprinted from Technical Digest IEEE Solid-State Sensor and Actuator Workshop, June 1990; pp. 198-202	
	C24	TORCHEUX, L. et al., "Electrochemical Coupling Effects on the Corrosion of Silicon Samples in HF Solutions," J. Electrochem.Soc., Vol. 142, No. 6, June 1995	
	C25	<i>Transducer Elements</i> , Piezo Systems, Inc., Cambridge MA, Catalog #3, 1998, pgs. 30-45.	
	C26	<i>Types and Characteristics of SDH Network Protection Architectures</i> , International Telecommunication Union (ITU-T), Recommendation G.941 October, 1998, pgs. 1-132.	
	C27	VANKESSEL, P. et al., "A MEMS-Based Projection Display," Proceedings of the IEEE, Vol. 86, No. 8, August 1998; pp. 1687-1704	
	C28	WONG, ARK-CHEW et al., <i>Anneal-Activated, Tunable, 68 MHz Micromechanical Filters</i> , Center for Integrated Microsystems, Dept. of Electrical Engineering and Computer Science, University of Michigan, Ann Arbor, Michigan 48109, Transducers '99, June 7-10, 1999, pp. 1390-1393, Sendai, Japan	

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